Ain Shams University Faculty of Girls for Arts, Science and Education Physics Department

Investigation of Some Physical Properties of SnS Thin Films Using Electrical and Optical Measurements



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By

AMAL FAWZY SHAFIK EL-DEEB

M.Sc. (1984)

Supervised By

Prof. Dr. MANSOUR MOHAMED HASSAB EL-NABI

Prof. Dr. HILMY TAHA EL-SHAIR

Ass. Prof. Dr. HODA SHEHATA SOLIMAN

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Ain Shams University
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Science and Education
Physics Department

Name of Student: AMAL FAWZY SHAFIK EL-DEEB

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Prof. Dr. HILMY TAHA EL-SHAIR

Ass. Prof.Dr. HODA SHEHATA SOLIMAN

Approved

Hanson H. El No

HodaShehata





قالوا سبحانك لا علم لنا إلا ما علمتنا إنك أنت العليم الحكيم.

صرق لافة العظيم

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إهــــداءِ

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